

ABSTRACT:

A high-frequency MEMS switch (10) comprises a signal conductor (12) which is arranged on a substrate (11) as well as an oblong-shaped switching element (13) which has a bent elastic bending area (133, 132) and is fastened on the substrate (11) in a cantilevered manner. An electrode arrangement (14a, 14b) is used for generating an electrostatic force which acts upon the switching element (13) in order to bend the switching element toward the signal conductor (12). The switching element (13) is arranged in its longitudinal direction parallel to the signal conductor (12), and it has a contact area (15) which extends transversely to the switch element (13) over the signal conductor (12). Under the effect of the electrostatic force, the elastic bending area (131, 132) of the switching element (13) progressively approaches the electrode arrangement (14a, 14b) in a direction parallel to the signal line (12). The switching element (13) has, for example, two mutually parallel extending switching arms (13a, 13b), which are mutually connected by a bridge as the contact area (15) and are arranged on both sides of the signal line (12) and parallel thereto.

[Figure 1]